

FORM PTO-1449

**LIST OF PATENTS AND OTHER ITEMS FOR APPLICANT'S
INFORMATION DISCLOSURE STATEMENT**

(Use several sheets if necessary)

ATTY. DOCKET NO.

02578.0006.CROSS01

SERIAL NO.

09/899,383

APPLICANT:

Scott A. Chalmers, et al.

FILING DATE:

July 3, 2001

GROUP:

2877

U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE
H8	4,555,767	11/26/85	Case et al.	364	563	10/28/92
H8	5,436,725	7/25/95	Ledger	356	357	10/12/93
H8	5,747,813	05/05/98	Norton et al.	250	372	04/14/94

FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB CLASS	TRANSLATION YES NO
H8	EP 0 644 399 A2	03/22/95	Europe (Dainippon Screen Mfg. Co. Ltd.)			
H8	EP 0 652 415 A1	05/10/95	European			
H8	EP 0 663 265 A1	07/19/95	Europe (International Business Machines Corporation)			

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)

H8	AD	Jones, G.R. et al., <i>Chromatic Interferometry for an Intelligent Plasma Processing System</i> , MEASUREMENT SCIENCE & TECHNOLOGY , Vol. 5, No. 6, June 1994 (1994-06), Pages 639-647, XP 000456344; Bristol, GB.
H8	AE	Lange, V. et al., <i>Reflexionsinterferometrie zur Kontrolle dünner Silizium-Membranen</i> , TECHNISCHES MESSEN , Vol. 61, No. 9, September, 1994 (1994-09), pages 346-351, XP000465894, pages 346-351, figures 1-4
	AF	<i>ImSpector</i> Imaging Spectrograph brochure including specifications, Spectral Imaging Ltd. , Oulu, Finland, (3 pages)
	AG	CCD Detectors, Optical Systems Division , retrieved on-line 6/21/00, (3 pages)
	AH	<i>Advanced Thin Film Measurements – About thin Film</i> , Filmetrics , retrieved on-line 6/21/00; pages 1-6
	AI	<i>Advanced Thin Film Measurements – Operation</i> , Filmetrics , retrieved on-line 6/21/00; pages 1-2
	AJ	<i>Advanced Thin Film Measurements – PTFEON Data</i> , Filmetrics , retrieved on-line 6/21/00; (1 page)
H8	AK	<i>Advanced Thin Film Measurements – faq</i> , Filmetrics , retrieved on-line 6/21/00; (2 pages)

EXAMINER:

[Signature]

DATE CONSIDERED:

4/4/03

EXAMINER: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include a copy of this form with next communication to applicant